Information & Control Japan TC Chapter

Meeting Summary and Minutes

Japan Standards Spring 2018 Meetings
April 26, 2018 Begin 13:30 – End 17:00
SEMI Japan, Tokyo, Japan

TC Chapter Announcements

Next TC Chapter Meeting
July 27, 2018, Begin 13:00 – End 17:00
SEMI Japan, Tokyo, Japan

Table 1 Meeting Attendees
*Italic*ics indicate virtual participants

**Co-Chairs:** Takayuki Nishimura (SCREEN Semiconductor Solutions), Mitsuhiro Matsuda (Hitachi Kokusai Electric)

**SEMI Staff:** Mizue Iwamura

<table>
<thead>
<tr>
<th>Company</th>
<th>First</th>
<th>Last</th>
<th>Company</th>
<th>First</th>
<th>Last</th>
</tr>
</thead>
<tbody>
<tr>
<td>ASM Japan K.K.</td>
<td>Yoshihisa</td>
<td>Takasaki</td>
<td>Tokyo Electron</td>
<td>Tadashi</td>
<td>Mochizuki</td>
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<tr>
<td>Hitachi Kokusai Electric</td>
<td>Mitsuhiro</td>
<td>Matsuda</td>
<td>Tokyo Electron</td>
<td>Naoko</td>
<td>Murata</td>
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<tr>
<td>IBM Japan Services</td>
<td>Osamu</td>
<td>Oishi</td>
<td>Tokyo Electron</td>
<td>Masaya</td>
<td>Nagata</td>
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<tr>
<td>MECHATROLINK Members Association</td>
<td>Atsunobu</td>
<td>Sakata</td>
<td>Toshiba Memory</td>
<td>Koji</td>
<td>Kitajima</td>
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<td>MECHATROLINK Members Association</td>
<td>Jumpei</td>
<td>Kondo</td>
<td>Yokogawa Solution Service</td>
<td>Takashi</td>
<td>Nakagawa</td>
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<tr>
<td>Mitsubishi Electric</td>
<td>Yuki</td>
<td>Fujita</td>
<td>Vistaideal Consulting</td>
<td>Terry</td>
<td>Asakawa</td>
</tr>
<tr>
<td>Murata Machinery</td>
<td>Shinichiro</td>
<td>Imoto</td>
<td>ZAMA Consulting</td>
<td>Mitsune</td>
<td>Sakamoto</td>
</tr>
<tr>
<td>Naigai TEC</td>
<td>Hideaki</td>
<td>Ogihara</td>
<td></td>
<td></td>
<td></td>
</tr>
<tr>
<td>SCREEN Semiconductor Solutions</td>
<td>Takayuki</td>
<td>Nishimura</td>
<td>SEMI Japan</td>
<td>Mizue</td>
<td>Iwamura</td>
</tr>
</tbody>
</table>

Table 2 Leadership Changes

<table>
<thead>
<tr>
<th>WG/TF/SC/TC Name</th>
<th>Previous Leader</th>
<th>New Leader</th>
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</thead>
<tbody>
<tr>
<td>None.</td>
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Table 3 Committee Structure Changes

<table>
<thead>
<tr>
<th>Previous WG/TF/SC Name</th>
<th>New WG/TF/SC Name or Status Change</th>
</tr>
</thead>
<tbody>
<tr>
<td>None.</td>
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<tr>
<td></td>
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</tbody>
</table>

Table 4 Ballot Results

<table>
<thead>
<tr>
<th>Document #</th>
<th>Document Title</th>
<th>Committee Action</th>
</tr>
</thead>
<tbody>
<tr>
<td>6300</td>
<td>New Standard: Guide for EDA Freeze Version</td>
<td>Failed, Returned to TF for rework</td>
</tr>
<tr>
<td>6319</td>
<td>Line Item Revision to: ‘SEMI E87-1017: Specification for Carrier Management (CMS)’</td>
<td></td>
</tr>
<tr>
<td>Line Item 1</td>
<td>Add ‘SEMI E171 Specification for Predictive Carrier Logistics (PCL)’ to the ‘Related Documents’ section.</td>
<td>Passed, as balloted</td>
</tr>
<tr>
<td>6330</td>
<td>Line Item Revisions to E54.17-0812 Specification of Sensor Actuator Network For A-Link</td>
<td>Passed, as balloted</td>
</tr>
<tr>
<td>Line Item 1</td>
<td>Adding reference and mapping about E54.22 ‘Specification for Sensor/Actuator Network Specific Device Model for Vacuum Pressure Gauge’ to proper sections of E54.17</td>
<td>Passed, as balloted</td>
</tr>
<tr>
<td>Line Item 2</td>
<td>Adding reference and mapping about E54.24 ‘Specification for Sensor/Actuator Network Specific Device Model of Generic Equipment Network Sensor’ to proper sections of E54.17</td>
<td>Passed, as balloted</td>
</tr>
<tr>
<td>6331</td>
<td>Line Item Revisions to E54.19-0308 (Reapproved 0614) Specification of Sensor/Actuator Network for MECHATROLINK</td>
<td></td>
</tr>
<tr>
<td>Line Item 1</td>
<td>Adding reference and mapping about E54.22 ‘Specification for Sensor/Actuator Network Specific Device Model for Vacuum Pressure Gauge’ to proper sections of E54.19</td>
<td>Passed, as balloted</td>
</tr>
<tr>
<td>Line Item 2</td>
<td>Adding reference and mapping about E54.24 ‘Specification for Sensor/Actuator Network Specific Device Model of Generic Equipment Network Sensor’ to proper sections of E54.19</td>
<td>Passed, as balloted</td>
</tr>
</tbody>
</table>

#1 Passed ballots and line items will be submitted to the ISC Audit & Review Subcommittee for procedural review.

#2 Failed ballots and line items were returned to the originating task forces for re-work and re-balloting or abandoning.

Table 5 Activities Approved by the GCS between meetings of the TC Chapter

<table>
<thead>
<tr>
<th>#</th>
<th>Type</th>
<th>SC/TF/WG</th>
<th>Details</th>
</tr>
</thead>
<tbody>
<tr>
<td>6330</td>
<td>SNARF</td>
<td>Sensor Bus TF</td>
<td>Line Item Revisions to E54.17-0812 Specification of Sensor Actuator Network for A-Link</td>
</tr>
<tr>
<td>6331</td>
<td>SNARF</td>
<td>Sensor Bus TF</td>
<td>Line Item Revisions to E54.19-0308 (Reapproved 0614) Specification of Sensor Actuator Network for MECHATROLINK</td>
</tr>
<tr>
<td>6331</td>
<td>Ballot</td>
<td>Sensor Bus TF</td>
<td>Ballot submission of #6331: Line Item Revisions to E54.19-0308 (Reapproved 0614) Specification of Sensor Actuator Network for MECHATROLINK to Cycle2-18</td>
</tr>
</tbody>
</table>
### Table 6 Authorized Activities

Listing of all revised or new SNARF(s) approved by the Originating TC Chapter.

<table>
<thead>
<tr>
<th>#</th>
<th>Type</th>
<th>SC/TF/WG</th>
<th>Details</th>
</tr>
</thead>
<tbody>
<tr>
<td>6374</td>
<td>SNARF</td>
<td>Sensor Bus TF</td>
<td>Line-Item Revision to SEMI E54.21-1110 (Reapproved 0517): Specification for Sensor Actuator Network for Motionnet® Communication</td>
</tr>
<tr>
<td>6376</td>
<td>SNARF</td>
<td>Sensor Bus TF</td>
<td>Line-Item Revision to SEMI E54.12-0614: Specification for Sensor/Actuator Network Communications for CC-Link</td>
</tr>
<tr>
<td>6377</td>
<td>SNARF</td>
<td>GEM300 TF</td>
<td>Line-Item Revision to SEMI E5-1217: SEMI Equipment Communications Standard 2 Message Content (SECS-II)</td>
</tr>
</tbody>
</table>

# SNARFs and TFOFs are available for review on the SEMI Web site at:

http://downloads.semi.org/web/wstdsbal.nsf/TFOFSNARF

### Table 7 Authorized Ballots

<table>
<thead>
<tr>
<th>#</th>
<th>When</th>
<th>TF</th>
<th>Details</th>
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<tbody>
<tr>
<td>6375</td>
<td>Cycle5 or 6-18</td>
<td>GEM300 TF</td>
<td>Revision to SEMI E170-1217: Specification for Secured Foundation of Recipe Management System (SFORMS), SEMI E170.1-1217: Specification for SECS-II Protocol for Secured Foundation of Recipe Management System</td>
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<tr>
<td>6376</td>
<td>Cycle5-18</td>
<td>Sensor Bus TF</td>
<td>Line-Item Revision to SEMI E54.12-0614: Specification for Sensor/Actuator Network Communications for CC-Link</td>
</tr>
<tr>
<td>6377</td>
<td>Cycle5 or 6-18</td>
<td>GEM300 TF</td>
<td>Line-Item Revision to SEMI E5-1217: SEMI Equipment Communications Standard 2 Message Content (SECS-II)</td>
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<tr>
<td>6300A</td>
<td>Cycle5 or 6-18</td>
<td>DDA TF</td>
<td>New Standard: Guide for EDA Freeze Version</td>
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### Table 8 SNARF(s) Granted a One-Year Extension

<table>
<thead>
<tr>
<th>#</th>
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<tr>
<td>None.</td>
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### Table 9 SNARF(s) Abolished

<table>
<thead>
<tr>
<th>#</th>
<th>TF</th>
<th>Title</th>
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</thead>
<tbody>
<tr>
<td>6324</td>
<td>GEM300 TF</td>
<td>Line Item Revision to SEMI E170-mmyy: Specification for Secured Foundation of Recipe Management System (SFORMS) to Change the Model Design</td>
</tr>
<tr>
<td>6325</td>
<td>GEM300 TF</td>
<td>Line Item Revision to SEMI E170-mmyy: Specification for Secured Foundation of Recipe Management System (SFORMS) to Describe the Relation of Structure of Multiple Recipes</td>
</tr>
</tbody>
</table>
Table 10 Standard(s) to receive Inactive Status

<table>
<thead>
<tr>
<th>Standard Designation</th>
<th>Title</th>
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<tbody>
<tr>
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Table 11 New Action Items

<table>
<thead>
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<th>Item #</th>
<th>Assigned to</th>
<th>Details</th>
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</thead>
<tbody>
<tr>
<td>20180426_1</td>
<td>Mizue Iwamura (SEMI Japan)</td>
<td>To ask HQ and IT support about the web migration for standards activities including task forces.</td>
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Table 12 Previous Meeting Action Items

<table>
<thead>
<tr>
<th>Item #</th>
<th>Assigned to</th>
<th>Details</th>
</tr>
</thead>
<tbody>
<tr>
<td>None.</td>
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</table>

1 Welcome, Reminders, and Introductions

Takayuki Nishimura (SCREEN Semiconductor Solutions) called the meeting to order at 13:30. The meeting reminders on antitrust issues, intellectual property issues and holding meetings with international attendance were reviewed. Attendees introduced themselves.

Attachment: 01_02_Required_Elements_Reg_20150327_E+J

2 Review of Previous Meeting Minutes

The TC Chapter reviewed the minutes of the previous meeting.

Motion: To approve the minutes of the previous meeting with as written
By / 2nd: Takashi Nakagawa (Yokogawa Solution Service) / Mitsune Sakamoto (ZAMA Consulting)
Discussion: None.
Vote: 13-0, Motion Passed.
Attachment: 02-00_Japan-I&C_Minutes_20171215_Draft_r2_Checked

3 Liaison Reports

3.1 Information & Control Europe TC Chapter

None.
3.2 Information & Control Korea TC Chapter
Mitsuhiro Matsuda (Hitachi Kokusai Electric) reported for the Information & Control Korea TC Chapter as attached.

Attachment: 03-02_KR_I&C_liaison_April_2018

3.3 Information & Control North America TC Chapter
Mitsuhiro Matsuda (Hitachi Kokusai Electric) reported for the Information & Control North America TC Chapter as attached.
Takayuki Nishimura (SCREEN) reported that James Moyne (Applied Materials) was interested in E170 which may relates to smart manufacturing.

Attachment: 03-03_NA IC Liaison Report April 2018

3.4 Information & Control Taiwan TC Chapter
Mitsuhiro Matsuda (Hitachi Kokusai Electric) reported for the Information & Control Taiwan TC Chapter as attached.

Attachment: 03-04_TW I&C Liaison Report March 2018_r1

3.5 Staff Report
Mizue Iwamura (SEMI Japan) gave the SEMI Staff Report. See attached file.

Attachment: 03-05_SEMI Staff Report 20180423_r0

4 Ballot Review
NOTE 1: TC Chapter adjudication on ballots reviewed is detailed in the Audits & Review (A&R) Subcommittee Forms for procedural review. The A&R forms are available as attachments to these minutes. The attachment number for each balloted document is provided under each ballot review section below.

4.1 Document #6300, New Standard: Guide for EDA Freeze Version
The ballot failed and 6300A will be submitted as in Cycle 6-2018.

Attachment: 04-01_6300_BallotReport_r1

4.2 Document #6319, Line Item Revision to: ‘SEMI E87-1017: Specification for Carrier Management (CMS)’
4.2.1 Line Item 1: Add ‘SEMI E171 Specification for Predictive Carrier Logistics (PCL)’ to the ‘Related Documents’ section.
Line Item 1 passed TC review as balloted and will be submitted to the ISC A&R for procedural review. Details can be found in the attached Procedural Review file.

Attachment: 04-02_6319_BallotReport
4.3 Document #6330, Line Item Revisions to E54.17-0812 Specification of Sensor Actuator Network For A-Link

4.3.1 Line Item 1: Title: Adding reference and mapping about E54.22 ‘Specification for Sensor/Actuator Network Specific Device Model for Vacuum Pressure Gauge’ to proper sections of E54.17

Line Item 1 passed TC review as balloted and will be submitted to the ISC A&R for procedural review. Details can be found in the attached Procedural Review file.

4.3.2 Line Item 2: Adding reference and mapping about E54.24 ‘Specification for Sensor/Actuator Network Specific Device Model of Generic Equipment Network Sensor’ to proper sections of E54.17

Line Item 2 passed TC review as balloted and will be submitted to the ISC A&R for procedural review. Details can be found in the attached Procedural Review file.

Attachment: 04-03_6330_BallotReport

4.4 Document #6331, Line Item Revisions to E54.19-0308 (Reapproved 0614) Specification of Sensor/Actuator Network for MECHATROLINK

4.4.1 Line Item 1: Adding reference and mapping about E54.22 ‘Specification for Sensor/Actuator Network Specific Device Model for Vacuum Pressure Gauge’ to proper sections of E54.19

Line Item 1 passed TC review as balloted and will be submitted to the ISC A&R for procedural review. Details can be found in the attached Procedural Review file.

4.4.2 Line Item 2: Adding reference and mapping about E54.24 ‘Specification for Sensor/Actuator Network Specific Device Model of Generic Equipment Network Sensor’ to proper sections of E54.19

Line Item 2 passed TC review as balloted and will be submitted to the ISC A&R for procedural review. Details can be found in the attached Procedural Review file.

Attachment: 04-04_6331_BallotReport_r1

5 Subcommittee and Task Force Reports

5.1 GEM300 TF

Masaya Nagata (Tokyo electron) reported for the GEM 300 Task Force. Of note;

- Last meeting is April 26, 2018, and next meeting is scheduled at 10:00 a.m. on May 8, 2108.
- 6319 was submitted for Cycle2-18, and ballot result was reviewed.
- Revision ballots for E5 and E170 will be submitted for Cycle5-18.
- E170 Application Study WG
  - Working Group Leader is Osamu Oishi.
- NA GEM 300 TF is interested in E170 and collaboration with Japan.

Attachment: 05-01_JA_ICC_GEM300_TF_Report_2018_0426_R0.0

5.2 Japan I&C Maintenance TF

Mitsuhiro Matsuda (Hitachi Kokusai Electric) reported that there are no activities currently working on.
5.3 Sensor Bus TF
Hideaki Ogihara (Naigai TEC) reported for the Sensor Bus Task Force. Of note;
- TF submitted E54 NCS Sub-documents for cycle-2
- Ballot Review in (4/17)
  - No Negative vote but a comment for each.
- E54 Preparing ballots of NCS sub-documents for cycle-5

Attachment: 05-03_SAB-TF Rpt0418pptx

5.4 Diagnostic Data Acquisition (DDA) TF
Mitsune Sakamoto (Zama Consulting) reported for the DDA Task Force. Of note;
- The last meeting was on April 25
- 6300 to fail and rework
- Takashi Nakagawa (Yokogawa Solution Service) attended NA Spring Meetings
- Report from NA Spring Meeting by Nakagawa-san
- Freeze 3 discussion
  - Applying Protocol Buffer – What about SOAP/XML?
  - Call for the trial to prove the PB performance
- Miscellaneous
  - #6338 E132 Major Revision – ballot by 2018/E
  - EDA Workshop SEMICON Japan 2018
  - Flaws in Standards

Attachment: 05-04_DDA_TF_20180425-02, 05-04_NA_DDA_SNARFS_20180426

5.5 Equipment Data Acquisition (EDA) Working Group
Mitsune Sakamoto (Zama Consulting) reported for the EDA Task Force. EDA TF is planning to have EDA Workshop at SEMICON Japan 2018.

6 Old Business
6.1 SNARF Project Period Check
Mizue Iwamura (SEMI Japan) addressed that there is no SNARF that exceed the project period.

6.2 5 Year Review Check
Mizue Iwamura (SEMI Japan) addressed that there is no documents that exceed.
7 New Business

7.1 SNARF for Line-Item Revision to SEMI E54.12-0614: Specification for Sensor/Actuator Network Communications for CC-Link

Hideaki Ogihara (Naigai TEC) addressed the committee on this topic.

Motion: To approve a SNARF for Line-Item Revision to SEMI E54.12-0614: Specification for Sensor/Actuator Network Communications for CC-Link.

By / 2nd: Hideaki Ogihara (Naigai TEC) / Mitsuhiro Matsuda (Hitachi Kokusai Electric)

Discussion: None.

Vote: 15-0, Motion Passed.

Attachment: 07-01_SNARF - E5412Rev_r1

7.2 Ballot Submission of #6376: Line-Item Revision to SEMI E54.12-0614: Specification for Sensor/Actuator Network Communications for CC-Link

Hideaki Ogihara (Naigai TEC) addressed the committee on this topic.

Motion: To approve ballot submission of #6376: Line-Item Revision to SEMI E54.12-0614: Specification for Sensor/Actuator Network Communications for CC-Link for Cycle5-18.

By / 2nd: Hideaki Ogihara (Naigai TEC) / Mitsuhiro Matsuda (Hitachi Kokusai Electric)

Discussion: None.

Vote: 14-0, Motion Passed.

7.3 SNARF for Line-Item Revision to SEMI E54.21-1110 (Reapproved 0517): Specification for Sensor Actuator Network for Motionnet® Communication

Hideaki Ogihara (Naigai TEC) addressed the committee on this topic.

Motion: To approve a SNARF for Line-Item Revision to SEMI E54.21-1110 (Reapproved 0517): Specification for Sensor Actuator Network for Motionnet® Communication.

By / 2nd: Hideaki Ogihara (Naigai TEC) / Mitsuhiro Matsuda (Hitachi Kokusai Electric)

Discussion: None.

Vote: 15-0, Motion Passed.

Attachment: 07-03_SNARF - E5421Rev_r2

7.4 Ballot Submission of #6374: Line-Item Revision to SEMI E54.21-1110 (Reapproved 0517): Specification for Sensor Actuator Network for Motionnet® Communication

Hideaki Ogihara (Naigai TEC) addressed the committee on this topic.


By / 2nd: Hideaki Ogihara (Naigai TEC) / Mitsuhiro Matsuda (Hitachi Kokusai Electric)

Discussion: None.

Vote: 15-0, Motion Passed.
7.5 Abolish the SNARF for Line Item Revision to SEMI E170-mmyy: Specification for Secured Foundation of Recipe Management System (SFORMS) to Change the Model Design

Osamu Oishi (IBM Japan Services) addressed the committee on this topic.

Motion: To abolish the SNARF for Line Item Revision to SEMI E170-mmyy: Specification for Secured Foundation of Recipe Management System (SFORMS) to Change the Model Design

By / 2nd: Osamu Oishi (IBM Japan Services) / Mitsuhiro Matsuda (Hitachi Kokusai Electric)

Discussion: None.

Vote: 14-0, Motion Passed.

7.6 Abolish the SNARF for Line Item Revision to SEMI E170-mmyy: Specification for Secured Foundation of Recipe Management System (SFORMS) to Describe the Relation of Structure of Multiple Recipes

Osamu Oishi (IBM Japan Services) addressed the committee on this topic.

Motion: To abolish the SNARF for Line Item Revision to SEMI E170-mmyy: Specification for Secured Foundation of Recipe Management System (SFORMS) to Describe the Relation of Structure of Multiple Recipes

By / 2nd: Osamu Oishi (IBM Japan Services) / Mitsuhiro Matsuda (Hitachi Kokusai Electric)

Discussion: None.

Vote: 15-0, Motion Passed.


Osamu Oishi (IBM Japan Services) addressed the committee on this topic.


By / 2nd: Osamu Oishi (IBM Japan Services) / Mitsuhiro Matsuda (Hitachi Kokusai Electric)

Discussion: None.

Vote: 15-0, Motion Passed.


Osamu Oishi (IBM Japan Services) addressed the committee on this topic.

Motion: To approve a SNARF for Revision to SEMI E170-1217: Specification for Secured Foundation of Recipe Management System (SFORMS), SEMI E170.1-1217: Specification For SECS-II Protocol for Secured Foundation of Recipe Management System

By / 2nd: Osamu Oishi (IBM Japan Services) / Mitsuhiro Matsuda (Hitachi Kokusai Electric)

Discussion: None.

Vote: 14-0, Motion Passed.

Attachment: 07-08_SNARF_for_Revision_to_E170-1217_SFORMS_2018_0410_2

Osamu Oishi (IBM Japan Services) addressed the committee on this topic.

**Motion:** To approve ballot submission of #6375: Revision to SEMI E170-1217: Specification for Secured Foundation of Recipe Management System (SFORMS), SEMI E170.1-1217: Specification for SECS-II Protocol for Secured Foundation of Recipe Management System for Cycle 5 or 6-18.

**By / 2nd:** Osamu Oishi (IBM Japan Services) / Mitsuhiro Matsuda (Hitachi Kokusai Electric)

**Discussion:** None.

**Vote:** 14-0, Motion Passed.

7.10 SNARF for Line-Item Revision to SEMI E5-1217: SEMI Equipment Communications Standard 2 Message Content (SECS-II)

Osamu Oishi (IBM Japan Services) addressed the committee on this topic.

**Motion:** To approve a SNARF for Line-Item Revision to SEMI E5-1217: SEMI Equipment Communications Standard 2 Message Content (SECS-II)

**By / 2nd:** Osamu Oishi (IBM Japan Services) / Mitsuhiro Matsuda (Hitachi Kokusai Electric)

**Discussion:** None.

**Vote:** 15-0, Motion Passed.

**Attachment:** 07-10_SNARF_for_LineItem_to_E5-1217_SFORMS_2018_0423_3

7.11 Ballot submission of #6377: Line-Item Revision to SEMI E5-1217: SEMI Equipment Communications Standard 2 Message Content (SECS-II)

Osamu Oishi (IBM Japan Services) addressed the committee on this topic.

**Motion:** To approve ballot submission of #6377: Line-Item Revision to SEMI E5-1217: SEMI Equipment Communications Standard 2 Message Content (SECS-II) for Cycle 5 or 6-18

**By / 2nd:** Osamu Oishi (IBM Japan Services) / Mitsuhiro Matsuda (Hitachi Kokusai Electric)

**Discussion:** None.

**Vote:** 15-0, Motion Passed.


Mitsune Sakamoto (ZAMA Consulting) addressed the committee on this topic.

**Motion:** To approve ballot submission of #6300A: New Standard: Guide for EDA Freeze Version for Cycle 5 or 6-18

**By / 2nd:** Mitsune Sakamoto (ZAMA Consulting) / Mitsuhiro Matsuda (Hitachi Kokusai Electric)

**Discussion:** None.

**Vote:** 15-0, Motion Passed.

7.13 SECS/GEM tutorial on June 26, 2018 and GEM 300 tutorial on June 27 on June 2018
8 Next Meeting and Adjournment

The next meeting is scheduled at 13:00 for July 27, 2018 at SEMI Japan, Tokyo, Japan. See http://www.semi.org/standards-events for the current list of events.

Adjournment: 17:00.

Respectfully submitted by:
Mizue Iwamura
Coordinator
SEMI Japan
Phone: +81.3.3222.5760
Email: miwamura@semi.org

Minutes tentatively approved by:

<table>
<thead>
<tr>
<th>Name of Approver</th>
<th>Date of Approval</th>
</tr>
</thead>
<tbody>
<tr>
<td>Takayuki Nishimura (SCREEN Semiconductor Solutions), Co-chair</td>
<td>June 22, 2018</td>
</tr>
<tr>
<td>Mitsuhiro Matsuda (Hitachi Kokusai Electric), Co-chair</td>
<td>June 22, 2018</td>
</tr>
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Table 13 Index of Available Attachments

<table>
<thead>
<tr>
<th>Title</th>
<th>Title</th>
</tr>
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<tbody>
<tr>
<td>01-02_Required_Elements_Reg_20150327_E+J</td>
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<td>02-00_Japan-I&amp;C_Minutes_20171215_Draft_r2_Checked</td>
<td>05-01_JA_ICC_GEM300_TF_Report_2018_0426_R0.0</td>
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#1 Due to file size and delivery issues, attachments must be downloaded separately. A .zip file containing all attachments for these minutes is available at www.semi.org. For additional information or to obtain individual attachments, please contact [SEMI Staff Name] at the contact information above.